

INFORMATION DISCLOSURE
CITATION

ATTY. DOCKET NO.

SERIAL NO.

4034-37

To be assigned

APPLICANT

IHARA, I. et al.

(Use several sheets if necessary)

FILING DATE

GROUP

June 26, 2003

unknown

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
JM	✓ 2001/0040717 A1	11/2001	MINOURA ET AL.	—	—	
JM	✓ 10/171,651	6/2002	MINOURA ET AL.	—	—	
JM	✓ 10/315,192	12/2002	IHARA ET AL.	—	—	
JM	✓ 10/327,951	12/2002	SAWAYAMA ET AL.	—	—	
JM	✓ 3,905,682	09/1975	MEYERBHOFFER	—	—	
JM	✓ 5,182,663	01/1993	JONES	—	—	
JM	✓ 6,067,134	05/2000	AKIYAMA ET AL.	—	—	
JM	✓ 2002-0149721 A1	10-2202	MINOURA ET AL.	—	—	
JM	✓ 2002-0154408 A1	10-2002	MINOURA ET AL.	—	—	

FOREIGN PATENT DOCUMENTS

DOCUMENT	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO
JM ✓ 07-205322	08/1995	JP	—	—	x
JM ✓ 3-186816	08/1991	JP	—	—	
JM ✓ 9-076245	03/1997	JP	—	—	
JM ✓ 8-321483 A	12-1996	JP	—	—	partial
JM ✓ 11-007008 A	1-1999	JP	—	—	partial
JM ✓ 2000-19490 A	1-2000	JP	—	—	partial
JM ✓ 10-260427	09/1998	JP	—	—	X
JM ✓ 98/57212	12/1998	WO	—	—	
JM ✓ 2000-221497	08/2000	JP	—	—	X
JM ✓ 54-105998 A	8-1979	JP	—	—	partial

OTHER DOCUMENTS (including Author, Title, Date, Pertinent pages, etc.)

JM	✓	NEUDECK ET AL; "PRECISION CRYSTAL CORNER CUBE ARRAYS FOR OPTICAL GRATINGS FORMED BY (100) SILICON PLANES WITH SELECTIVE EPITAXIAL GROWTH"; Applied Optics, vol. 35, no. 19, 01 July 1996, pages 3466-3470
JM	✓	Kaneko, "Control of Atomic Arrangement by Inverse Epitaxy (Semiconductor Atomic Layer Process by On-the-Spot Etching Technique)", "Reports of Research and Development Results in 1998 Academic Research Backup Project", Published by Hyogo Science and Technology Association, November 1999 and partial English translation thereof
JM	✓	"Encyclopedia of the eye, the web version", Okuzawa, July, 1999, pgs. 1-22
JM	✓	HASHIMOTO, K ET AL; "INVITED PAPER: REFLECTIVE COLOR DISPLAY USING CHOLESTERIC LIQUID CRYSTALS"; SID International Symposium Digest of Technical Papers; May 1998; pages 897-900; ISSN0098-966X

*Examiner

John McPherson

Date Considered

11/16/05

Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to application.